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Effects of Load and Humidity on Friction Fade-out at DLC Films Slid by ZrO₂ Pins in H₂-N₂ Gas Mixture Environment

TRACK OR CATEGORY

Materials Tribology III

AUTHORS AND INSTITUTIONS

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INTRODUCTION

Friction tests using fully hydrogenated DLC film against ZrO₂ pins under H₂ gas containing small amount of ethanol vapor were reported in authors' previous reports [1,2]. It was shown that the friction coefficient dropped to the friction tester noise level as low as 0.0001, which we termed friction fade-out (FFO). Since H₂ gas is hazardous by nature because of the risk of explosion and a wide range of flammability limits in air, i.e. from 4.1% to 74%. We attempted to reduce the H₂ content in the H₂-N₂ gas mixture by changing the main flow from dry H₂ gas to dry N₂ gas, and FFO under H₂-N₂ gas mixture is reported in this report.

For more information of FFO, the tribofilm made on ZrO₂ surface was investigated using FT-IR and TOF-SIMS (time-of-flight secondary ion mass spectrometry) analyses, where deuterated ethanol was used. It was found that a large amount of D- ions were included in the tribofilm, suggesting that the ethanol was dehydrated by a catalytic action of ZrO₂ and remained C₂H₄ contributed to form the tribofilm on ZrO₂. It will be shown that FFO depended a great deal on a humidity of environmental gas.

FRICITION TEST

An ion vapor deposition system was used in the present study to produce DLC films (NPS-330S, Nanotec Corp.). The source gas was introduced into the vacuum chamber and was then ionized by thermal electrons emitted from an anode. Carbon or hydrocarbon ions were attracted by the pulsed negative-bias voltage applied to the electrode, on which sample substrates were fixed and ions were deposited onto the substrates. Si (100) wafers (R_a : 0.12 nm, thickness: 525 μ m) were prepared for use as sample substrates and were ultrasonically cleaned in ethanol, followed by acetone. After placing the Si substrate on the bias electrode in the chamber, the chamber was pumped down to a base pressure of 3×10^{-3} Pa and Ar⁺ ion bombardment was performed for 30 min. For test samples, a 1200-nm-thick DLC layer was deposited using a C₇H₈-H₂ gas mixture with a bias voltage of -4.0 kV. The temperature of the heater near the sample was maintained at 230 °C throughout the deposition. H content of sample DLC, measured by Elastic Recoil Detection Analyzer (ERDA, KOBELCO, HRBS-1000), was larger value, e.g. 60 %, at the surface, but decreased down to 20 % at the depth of 10 nm by Ar ion etching and kept constant at deeper layer.

Friction tests were conducted using a pin-on-disk friction tester (FPR-2000, RHESCA INC.) in the reciprocating mode. A ZrO₂ pin was placed on a DLC sample fixed on the disk. The disk reciprocated at a constant speed of 7.2 mm/s, with a single sliding corresponding to 4.3 mm, and at a maximum applied load of 63.7 N corresponding to the maximum Hertzian pressure of 2.6 GPa. The test area including the

disk and pin was covered with a double plastic casing, but without seals, namely the test area was kept at the pressure of the atmosphere. The friction tester and supplied gas system is shown in Figure 1.

TEST RESULTS

Friction test results obtained in an H₂-N₂ gas mixture environment is shown in Figure 2. During run-in process in this test, an applied load was increased in a stepwise from 19.8 N to 63.7 N under a gas mixture of dry N₂ and ethanol-vapored H₂ gas. Their flow rates were 4.3 slm and 40 sccm, respectively. Then, the ethanol-vapored H₂ gas flow was reduced. When the flow rate of ethanol-vapored H₂ gas reached 5 sccm, the friction coefficient sharply dropped down to 0.0001, and remained constant for over 7 hours.

With a reduction in ethanol-vapored H₂ gas, a relative humidity at the section was also reduced. It will be shown that the steep reduction in friction coefficient from 0.01 to 0.0001 as shown in Figure 2 appears when the relative humidity reduces to around 1%. This relative humidity of 1% when FFO appears is almost identical in almost all cases.

ANALYSIS OF TRIBOFILM

By many observations using an optical microscope and SEM, it was found the contact area of ZrO₂ was covered with tribofilm during FFO sliding. We also found the formation of tribofilm is important for the occurrence of FFO, since the tribofilm was found to be peeled off at the observation after FFO disappearance. We analyzed the tribofilm before, during and after FFO, by SEM, FTIR, TOF-SIMS and nano-indenter.

Figure 3 shows an example of FT-IR spectrum of tribofilm at ZrO₂ surface after test, which indicates -CH peaks (2900~3000 cm⁻¹) originated from aliphatic hydrocarbon and -C=O peak (1720cm⁻¹) originated from carbonyl groups. We also analyzed the tribofilm by TOF-SIMS using deuterated-ethanol-vapored H₂ gas in order to clarify the role of ethanol molecules added to H₂ gas. Figure 4 shows example of secondary ion images on ZrO₂ and DLC surfaces those occurring FFO analyzed by TOF-SIMS, and found that ethanol is dehydrated and remained -CH (alkyl group) is included into the tribofilm during run-in process. More information obtained by analysis and effects of applied load and humidity will be reported at the presentation.

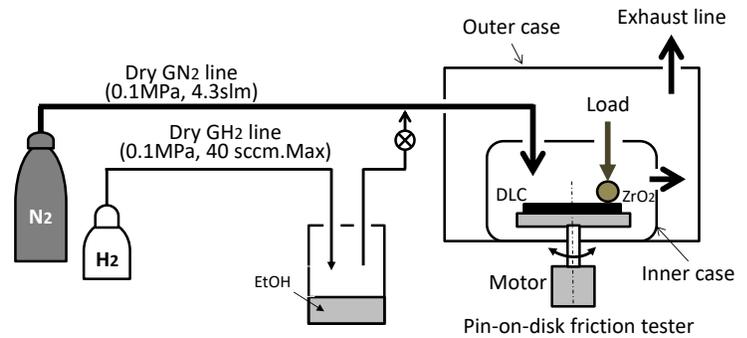


Figure1. Friction tester and supplied gas system

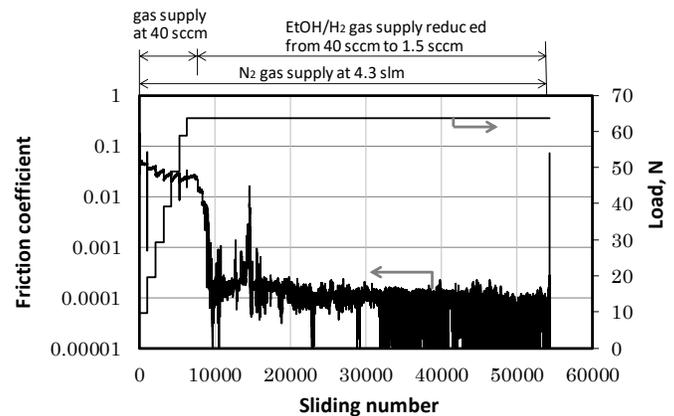


Figure 2. FFO under H₂-N₂ gas mixture environment

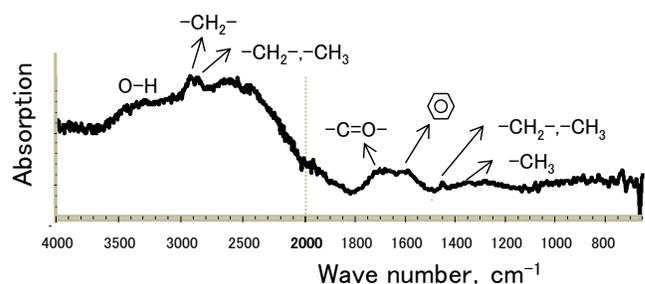


Figure 3 FT-IR spectrum of tribofilm

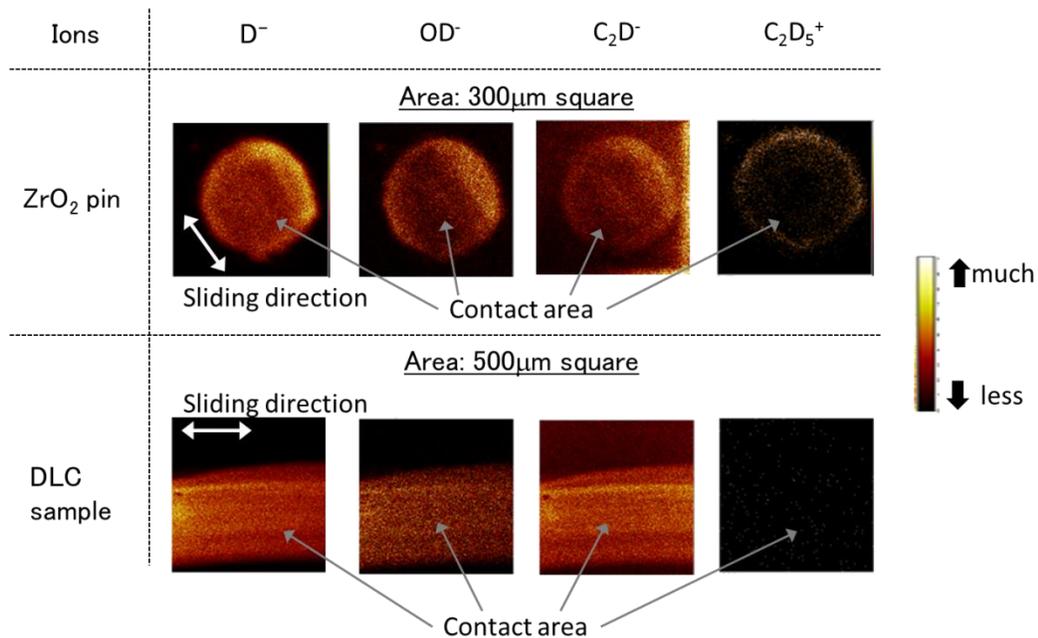


Figure 4 Secondary ion images of tribofilms analyzed by TOF SIMS

SUMMARY

ZrO₂ pin was slid against hydrated-DLC film under ethanol-vapored H₂-N₂ gas mixture, and a sharp friction reduction down to 0.0001 (FFO) was reported. FFO appeared by a stepwise increase in load and followed decrease in the supply

Tribofilm formed on the ZrO₂ surface plays important role for the occurrence of FFO, and tribofilm is analyzed by many method. An effect of relative humidity on friction reduction will be also shown in detail at the presentation.

REFERENCES

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KEYWORDS

Carbon, Graphite, Ceramics